



PATENT
Customer No. 22,852
Attorney Docket No. 03180.0343

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Masafumi ASANO et al.

Application No.: 10/725,571

Filed: December 3, 2003

For: RETICLE SET, METHOD FOR
DESIGNING A RETICLE SET, EXPOSURE
MONITORING METHOD, INSPECTION METHOD
FOR RETICLE SET AND MANUFACTURING
METHOD FOR A SEMICONDUCTOR DEVICE

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) Group Art Unit: 1756
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) Examiner: Stephen D. Rosasco
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) Confirmation No.: 5144
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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

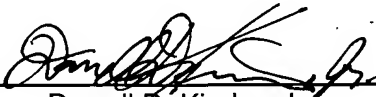
In a restriction requirement dated October 26, 2005, the Examiner required restriction under 35 U.S.C. § 121 between Group I, claims 1-10, characterized by the Examiner as being drawn to a reticle set; Group II, claims 11-17, characterized by the Examiner as being drawn to an exposure monitoring and inspecting method; and Group III, claims 18-22, characterized by the Examiner as being drawn to a method of manufacturing an integrated circuit.

Applicants provisionally elect to prosecute Group I, claims 1-10, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: November 28, 2005

By: 
Darrell D. Kinder, Jr.
Reg. No. 57,460